



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Kam-Leung, et al.

Serial No.: 10/627,753

Group Art Unit: 2823

Filed: July 28, 2003

Examiner: Brook Kebede

For: METHOD FOR SLOWING DOWN DOPANT-ENHANCED DIFFUSION  
SUBSTRATES AND DEVICES FABRICATED THEREFROM

Honorable Commissioner for Patents  
Alexandria, VA 22313-1450

**SUBMISSION OF CORRECTED FORM 1449**

Sir:


Submitted herewith is a corrected Form 1449. The Information Disclosure Statement filed December 8, 2004 included a minor typographical in the form PTO-1449.

That is, the form PTO-1449 cited U.S. Patent Application Publication No. 2003/009640 A1. The correct U.S. Patent Application Publication No. should read --"2003/0096420 A1"--, which Publication was the one submitted. Applicants have attached a corrected form PTO-1449, correcting the above-identified typographical error.

Please note that the attached form PTO-1449 is not a new submission. The attached form PTO-1449 is merely a corrected form PTO-1449.

Acknowledgment of receipt is respectfully requested.

Respectfully submitted,

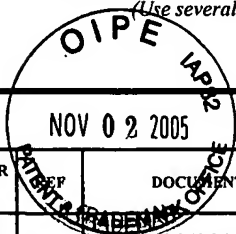
  
\_\_\_\_\_  
Scott M. Tulino, Esq.  
Registration No. 46,060

Sean M. McGinn, Esq.  
Registration No. 34,386

Date: November 2, 2005  
**MCGINN INTELLECTUAL PROPERTY  
LAW GROUP, PLLC**  
Intellectual Property Law  
8321 Old Courthouse Road, Suite 200  
Vienna, VA 22182-3817  
(703) 761-4100  
**Customer No. 21254**

# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)



Docket Number (Optional)

YOR920030077US1

Application Number

10/627,753

Applicant(s)

Kam-Leung, et al.

Filing Date

July 28, 2003

Group Art Unit

2823

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		US 2003/0096490 A1	5/22/03	John Borland, et al.			
		6,518,150 B1	02/11/03	Matsumoto			
		6,069,062	05/30/00	Downey			
		6,180,476 B1	01/30/01	Yu			
		6,380,053 B1	04/30/02	Komatsu			
		6,426,278 B1	07/30/02	Nowak, et al.			
		6,087,209	07/11/00	Yeap, et al.			
		6,410,393 B1	06/25/02	Hao, et al.			

## FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		WO 97/42652	11/13/97	PCT				

## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

		Article by T. H. Huang, et al.: "Influence of Fluorine Preamorphization on the Diffusion and Activation of Low-Energy Implanted Boron During Rapid Thermal Annealing", Applied Physics Letters, American Institute of Physics, NY, US Vol. 65, No. 14, October 3, 1994, pp. 1829-1831.
		Article by S. Saito, et al.: "Defect Reduction by MeV i on Implantation for Shallow Junction Formation, Applied Physics Letters, American Institute by Physics, Vol. 63, No. 2, July 12, 1993, pp. 197-199.

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>INFORMATION DISCLOSURE CITATION</b> <i>(Use several sheets if necessary)</i>		Docket Number (Optional) <b>YOR920030077US1</b>		Application Number <b>10/627,753</b>	
		Applicant(s) <b>Kam-Leung, et al.</b>			
		Filing Date <b>July 28, 2003</b>		Group Art Unit <b>2823</b>	
<b>*EXAMINER INITIAL</b>		<b>OTHER DOCUMENTS</b> <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>			
		PCT International Search Report dated October 8, 2004.			
		PCT Written Opinion of the International Searching Authority.			
<b>EXAMINER</b>		<b>DATE CONSIDERED</b>			
<b>*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</b>					